



## PATENT APPLICATION

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q58716

Group Art Unit: 1756

Masayuki NAYA, et al.

Appln. No.: 09/649,013

Examiner: Martin J. Angebranndt

Confirmation No.: 7581

Filed: August 28, 2000

OPTICAL WAVELENGTH CONVERTING DEVICE AND PROCESS FOR

PRODUCING THE SAME

## AMENDMENT UNDER 37 C.F.R. § 1.111

Commissioner for Patents Washington, D.C. 20231

Sir:

For:

In response to the Office Action dated November 27, 2002, please amend the aboveidentified application as follows:

## **IN THE SPECIFICATION:**

The specification is changed as follows:

Page 35, delete last paragraph, continuing on to page 36.

Examples of the resist materials, which may be employed for the second resist layer 32, include the resist materials described in U.S. Patent Nos. 5338818, 5422223, 5866306, 5385804, 5399462, 5238773, 4481049, 4689289 and 4822716; and EP No. 229629A1. Further, the resist materials shown in the following formula, which are disclosed in Japanese Unexamined Patent Publication No. 7(1995)-114188, can be employed for the second resist layer 32.

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